

USSN 10/815,387
Attorney Docket No. 2003-0092-01

REMARKS

Claims 1-64 are active and pending in the present application. Claims 65-102 were previously withdrawn.

The 35 U.S.C. § 102(b) Rejections

Claims 1-48 stand rejected under 35 U.S.C. § 102(b) as being anticipated by U.S. Patent No. 5,373,523 to Fujimoto et al. (hereinafter, *Fujimoto*).

Applicants' independent Claim 1 relates to a high power high repetition rate gas discharge laser UV light source having a gas discharge chamber comprising an interior wall comprising a vertical wall and an adjacent bottom wall. The laser UV light source also has a gas circulation fan creating a gas flow path adjacent the interior vertical wall and the adjacent bottom wall, and an in-chamber dust trap positioned a region of low gas flow.

Applicants respectfully submit that *Fujimoto* does not show or suggest Applicants' claimed "in-chamber dust trap positioned a region of low gas flow." Applicants contend that the chamber 22 shown in FIG. 1 of *Fujimoto*, which contains front side mesh filter 13a and rear side mesh filter 13b, is a *separate chamber* from chamber 21, which is the gas discharge chamber filled with laser medium gas. See, e.g., *Fujimoto*, col. 5, lines 3-32 and FIG. 1. Accordingly, Applicants contend that *Fujimoto* fails to show or suggest an *in-chamber* dust trap. Applicants further contend *Fujimoto* does not show or suggest that the in-chamber dust trap is positioned in a region of low gas flow. Front side mesh filter 13a and rear side mesh filter 13b, as described, e.g., in col. 6, lines 2-5 of *Fujimoto*, perform such as to cause a pressure drop across each mesh filter (e.g., at least about 10 mm Aq). Applicants contend that *causing a pressure drop* across a filter, as in *Fujimoto*, does not show or suggest *positioning* an in-chamber dust trap *in a region of low gas flow* as in Applicants' claimed invention. For example, as shown in Applicants' FIG. 7, traps 280 are placed in low gas flow regions. These regions are in pockets formed between the main insulator 42 and the top half 22 of the chamber. Gas pressure and circulation will tend to move debris toward the traps 280 and once the

USSN 10/815,387
Attorney Docket No. 2003-0092-01

RECEIVED
CENTRAL FAX CENTER

JUL 05 2007

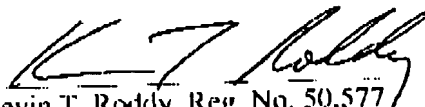
debris passes through the dust traps, e.g., into the pockets 282, it will be difficult for the debris to be caused to return back through the traps 280 to return into the gas flow.

For at least the above reasons, Applicants submit that *Fujimoto* does not show or suggests all of the elements of Applicants' Claim 1. Accordingly, Applicants respectfully submit that Claim 1 is in condition for allowance. Applicants further submit that Claims 2-64, which depend from Claim 1, are also allowable for at least the reasons discussed above.

Conclusion

Applicants authorize the Commissioner to charge \$120.00 to our Deposit Account No. 03-4060 for the one-month extension of time fee. Applicants do not believe that any other fees or charges are due for the continuing prosecution of the above captioned U.S. Patent Application, but in the event that there are the Commissioner is hereby authorized to charge the Deposit Account of applicants' assignee, Cymer, Inc. Deposit Account No. 03-4060 for any such fees or charges.

Respectfully submitted,


Kevin T. Roddy, Reg. No. 50,577

July 5, 2007
Cymer, Inc.
17075 Thornmint Court, MS 4/2C
San Diego, CA 92127
Customer No. 21773
Telephone: (858) 385-7185
Facsimile: (858) 385-6025